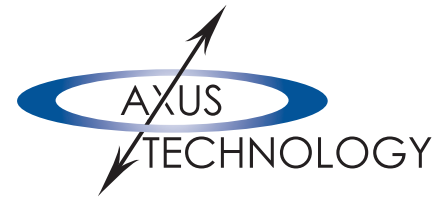


Axis Vacuum System



Your source for leading-edge surface processing solutions



Axis Technology introduces a completely automated process vacuum system for wafer backgrinding tools and polishers with back-referencing wafer carriers. Two systems are available:

- Stand alone, vacuum pumping plant with automatic fluid drain system.
 - Vacuum pump
 - Vacuum holding tank
 - Fluid collection tank with automatic drain system
- Wall-mount, vacuum holding plant with automatic fluid drain system.
 - This system connects to the house-vacuum system.
 - Vacuum holding tank
 - Fluid collection tank with automatic drain system

STAND ALONE DIMENSIONS

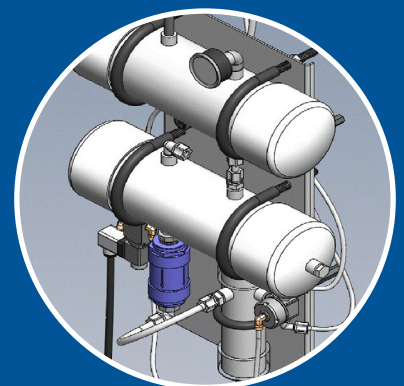
Metric	774.7mmW x 536.7mmD x 1495.5mmH	
Inches	30.5"W x 21.13"D x 58.88"H	
Weight	~68 kg	150 lbs
Power Req.	120v, 1 ph, 50/60 Hz, 10 amps	

WALL MOUNT DIMENSIONS

Metric	421.6mmW x 236.2mmD x 762mmH	
Inches	16.6"W x 9.3"D x 30"H	
Weight	~12.25 kg	27 lbs
Power Req.	120v, 1 ph, 50/60 Hz, <10 amps	

FEATURES

- Excellent systems for integration with Wafer Grinders.
- Provides vacuum draw while automatically separating and draining fluids from the system.
- Easy installation in the fab environment.
- Direct connection to most wafer grinders.
- Compact systems requiring minimal floor space.
- Can be located in the gray area outside the typical clean room.
- Low maintenance
- Incorporates commercially available spare parts.



Wall Mount Option